



Attorney Docket No.: **SSI-00700**

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

RE-PATENT
AUG 29 2001

TO 2800 MAIL ROOM

In re Application of:

Maximilian A. Biberger *et al.*

Serial No.: 09/704,641

Filed: November 1, 2000

For: **METHOD AND APPARATUS FOR
SUPERCritical PROCESSING
OF A WORKPIECE**

) Group Art Unit: 2812

) Examiner:

) **SUPPLEMENTAL INFORMATION**
) **DISCLOSURE STATEMENT**

) 260 Sheridan Avenue, Suite 420
) Palo Alto, California 94306
) (650)833-0160

Assistant Commissioner for Patents
Washington, D.C. 20231

Sir:

The citations listed below, copies attached, may be material to the examination of the above-identified application, and are therefore submitted in compliance with the duty of disclosure defined in 37 C.F.R. §§ 1.56 and 1.97. The Examiner is requested to make these citations of official record in this application.

Applicants have become aware of the following printed publications which may be material to the examination of this application:

- U.S. Patent No. 4,592,306;
- U.S. Patent No. 4,670,126;
- U.S. Patent No. 4,825,808;
- U.S. Patent No. 4,951,601;
- U.S. Patent No. 5,934,856;
- U.S. Patent No. 6,077,321;
- European Publication No. EP 0 244 951 A2;
- European Publication No. EP 0 272 141 A2;
- Great Britain Publication No. GB 2 193 482 A;
- Japanese Patent Abstract JP 10-144757;
- Japanese Patent Abstract JP 56-142629;

- 1 -

CERTIFICATE OF MAILING (37 CFR § 1.8(a))

I hereby certify that this paper (along with any referred to as being attached or enclosed) is being deposited with the U.S. Postal Service on the date shown below with sufficient postage as first class mail in an envelope addressed to the: Assistant Commissioner for Patents, Washington D.C. 20231

HAVERSTOCK & OWENS LLP.

Date: 8/22/2001 By: John D. Russian



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- Japanese Patent Abstract JP 60-238479;
- Japanese Patent Abstract JP 60-246635;
- Japanese Patent Abstract JP 61-231166;
- Japanese Patent Abstract JP 63-303059;
- PCT Publication No. WO 87/07309;
- PCT Publication No. WO 91/12629;
- PCT Publication No. WO 99/18603; and
- Hideaki Itakura et al., "Multi-Chamber Dry Etching System", Solid State Technology, April 1982, Page. 209-214.

This Supplemental Information Disclosure Statement under 37 C.F.R. §§ 1.56 and 1.97 is not to be construed as a representation that a search has been made, that additional information material to the examination of this application does not exist, or that anyone or more of these citations constitutes prior art.

Respectfully submitted,
HAVERSTOCK & OWENS LLP

Dated: 8-21-01

By: Thomas B. Haverstock
Thomas B. Haverstock
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Attorneys for Applicants

2812



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THE UNITED STATES PATENT AND TRADEMARK OFFICE

Inventor: Maximilian A. Biberger *et al.*
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) Group Art Unit: 2812
)
) Examiner:
) **TRANSMITTAL LETTER**
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) (650)833-0160

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Assistant Commissioner for Patents
Washington, D.C. 20231

Sir:
Enclosed please find a Supplemental Information Disclosure Statement, and Form PTO-1449, including copies of the references contained thereon, for filing in the U.S. Patent and Trademark Office.

The Commissioner is hereby authorized to charge any additional fee or credit overpayment to our Deposit Account No. 08-1275. **An originally executed duplicate of this transmittal is enclosed for this purpose.**

Respectfully submitted,
HAVERSTOCK & OWENS LLP

Dated: 8-21-01

By: Thomas B. Haverstock
Thomas B. Haverstock
Reg. No.: 32,571

Attorneys for Applicants

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HAVERSTOCK & OWENS LLP

Date: 8/22/2001 By: John D. Rarson